



PATENT  
2342-111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

APPLICANT: Kazuyuki TOYODA et al.  
APPL. NO.: 08/905,971 GROUP: 1763  
FILED: August 5, 1997 EXAMINER: R. Zervigon  
FOR: SUBSTRATE PROCESSING APPARATUS

H12B  
10/3/00  
MW

REPLY UNDER 37 C.F.R. §1.111

Assistant Commissioner for Patents  
Washington, D.C. 20231

September 27, 2000

Sir:

In reply to the Office Action dated March 27, 2000, the period for response having been extended for three (3) months to September 27, 2000, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please add the following new claims:

--27. A substrate processing apparatus as recited in claim 1, wherein the apparatus is configured to transfer and process a single substrate at a time.

28. A substrate processing apparatus as recited in claim 1, wherein the apparatus is configured to transfer a single substrate and to process a plurality of substrates at a time.

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